RADICAL PLASMA SOURCE (REMOTE PLASMA SOURCE) - MA2000C-863BB

Categories: Plasma components

ADDITIONAL INFORMATION

Typ	Radical plasma source (Remote Plasma Source)
Process	Etching & Deposition
Output Connection Type	
Dielectric material	Sapphire
Mains voltage nominal [V]	230 / 208
Output Power CW [W]	2000
Frequency [MHz]	2450

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